

CLAIMS

What is claimed is:

- 1           1. A method for forming a photonic-crystal filament, the method  
2 comprising the steps of:
  - 3           a) mixing a slurry comprising particles of substantially uniform size and a  
4 precursor material for a desired metal;
  - 5           b) urging the slurry through an orifice to force the particles and precursor  
6 material into a combination having a desired crystallographic configuration;
  - 7           c) drying the combination emerging from the orifice; and
  - 8           d) sintering the precursor material, whereby a photonic-crystal filament is  
9 formed.
- 1           2. A photonic-crystal filament made by the method of claim 1.
- 1           3. The method of claim 1, further comprising the step of:  
2           e) compressing the slurry.
- 1           4. The method of claim 1, further comprising the step of:  
2           f) heating the dried combination to remove the particles.
- 1           5. The method of claim 4, wherein the heating step f) and the sintering  
2 step d) are performed simultaneously.
- 1           6. The method of claim 1, wherein the particles comprise an inert  
2 material.
- 1           7. The method of claim 1, wherein the precursor material comprises a  
2 metal oxide.
- 1           8. The method of claim 1, further comprising the step of:  
2           g) reducing the precursor material to metallic form.

1           9. The method of claim 8, wherein step g) of reducing the precursor  
2 material comprises heating the precursor material in a reducing environment.

1           10. The method of claim 9, wherein the reducing environment comprises  
2 a gas selected from the list consisting of hydrogen, forming gas, a carbide gas,  
3 acetylene, and mixtures thereof.

1           11. The method of claim 1, further comprising the step of:  
2 h) providing a core filament and feeding the core filament through the  
3 orifice while urging the slurry through the orifice to force the particles and  
4 precursor material into a combination surrounding the core filament.

1           12. The method of claim 11, further comprising the step of:  
2 i) passing an electric current through the core filament, whereby the core  
3 filament is heated.

1           13. The method of claim 12, wherein the electric current heats the  
2 precursor material to an effective temperature for sintering the precursor  
3 material.

1           14. The method of claim 11, further comprising the step of:  
2 j) removing the core filament after the precursor material is sintered.

1           15. The method of claim 1, further comprising the step of:  
2 k) compressing the precursor material within a sheath.

1           16. The method of claim 15, wherein the sheath comprises a metal.

1           17. The method of claim 16, wherein the metal of the sheath comprises  
2 copper.

1           18. The method of claim 15, wherein step k) of compressing the  
2 precursor material is performed by drawing the sheath through at least one die.

1           19. The method of claim 18, wherein step k) of compressing the  
2 precursor material is performed by drawing the sheath through a series of two or  
3 more successively smaller dies.

1           20. The method of claim 15, wherein the sheath comprises a gas-  
2 permeable material.

1           21. The method of claim 15, further comprising the step of:  
2 l) removing the sheath after the precursor material is sintered.

1           22. The method of claim 15, further comprising the step of:  
2 m) providing a core filament and feeding the core filament through the orifice  
3 while urging the slurry through the orifice to force the particles and precursor  
4 material into a combination surrounding the core filament and while  
5 compressing the precursor material within the sheath.

1           23. The method of claim 22, further comprising the step of:  
2 n) removing the sheath after the precursor material is sintered.

1           24. The method of claim 22, further comprising the step of:  
2 o) removing both the sheath and the core filament after the precursor material is  
3 sintered.

1           25. A photonic-crystal filament made by the method of claim 15.

1           26. The method of claim 1, wherein the desired metal is a refractory  
2 metal.

1           27. The method of claim 27, wherein the refractory metal is selected  
2 from the list consisting of tungsten, platinum, tantalum, molybdenum, and alloys  
3 thereof.

1           28. The method of claim 1, wherein the desired metal is tungsten or an  
2 alloy thereof.

1           29. The method of claim 1, wherein the precursor material comprises an  
2 oxide of tungsten.

1           30. The method of claim 1, wherein the precursor material comprises  
2 peroxopolytungstic acid.

1           31. The method of claim 1 wherein the particles comprise substantially  
2 spherical particles.

1           32. The method of claim 1 wherein the particles comprise non-spherical  
2 particles.

1           33. The method of claim 1 wherein the particles comprise polymer  
2 particles.

1           34. The method of claim 1 wherein the particles comprise polymer  
2 nanospheres.

1           35. The method of claim 34, wherein the polymer particles comprise a  
2 material selected from the list consisting of polystyrene, polyethylene,  
3 polymethylmethacrylate (PMMA), latex, and combinations thereof.

1           36. The method of claim 1, wherein the photonic-crystal filament has a  
2 desired photonic band-gap, and the substantially uniform size of the particles is  
3 adapted to provide the desired photonic band-gap.

1           37. The method of claim 37, wherein the desired photonic band-gap has  
2 a lower wavelength edge and the substantially uniform size of the particles is  
3 chosen to be about one-quarter the value of the lower wavelength edge of the  
4 desired photonic band-gap.

1           38. The method of claim 37, wherein the desired photonic band-gap  
2 corresponds to a wavelength between about 400 nanometers and about 7000  
3 nanometers.

1           39. The method of claim 37, wherein the desired photonic band-gap  
2 corresponds to a wavelength between about 1200 nanometers and about 1800  
3 nanometers.

1           40. The method of claim 1, wherein the photonic-crystal filament has a  
2 longitudinal axis and a selected crystallographic axis of the desired  
3 crystallographic configuration is aligned parallel to the longitudinal axis of the  
4 photonic-crystal filament.

1           41. A lamp filament made by the method of claim 1.

1           42. An incandescent lamp comprising a photonic-crystal filament made  
2 by the method of claim 1.

1           43. A light source comprising the incandescent lamp of claim 43.

1           44. A method of cladding a metal filament, the method comprising the  
2 steps of:

3           a) providing a metal filament;

4           b) mixing a slurry comprising particles of substantially uniform size and a  
5 precursor material for a desired metal;

6 c) urging the metal filament and the slurry through an orifice to force the  
7 particles and precursor material into a combination having a desired crystal  
8 configuration surrounding the metal filament;

9 d) drying the combination emerging from the orifice;

10 e) sintering the precursor material; and

11 f) compressing the precursor material within a sheath, while drawing the  
12 filament through a series of two or more successively smaller dies, whereby the  
13 filament is clad with a photonic crystal.

1 45. The clad filament formed by the cladding method of claim 45.

1 46. The method of claim 45, further comprising the step of:

2 g) compressing the slurry.

1 47. The method of claim 45, further comprising the step of:

2 h) heating the dried combination to remove the particles.

1 48. The method of claim 48, wherein the heating step h) and the sintering  
2 step e) are performed simultaneously.

1 49. The method of claim 45, wherein the particles comprise an inert  
2 material.

1 50. The method of claim 45, wherein the precursor material comprises a  
2 metal oxide.

1 51. A photonic crystal for covering a filament core, the photonic crystal  
2 comprising:

3 a first refractory metal substantially filling interstitial spaces between a set  
4 of substantially spherical voids disposed in a predetermined crystallographic  
5 lattice,

6 the set of spherical voids being disposed surrounding the filament core.

1           52. The photonic crystal of claim 52, wherein the filament core  
2 comprises a second refractory metal.

1           53. The photonic crystal of claim 53, wherein the first and second  
2 refractory metals comprise different metals.

1           54. The photonic crystal of claim 53, wherein the first and second  
2 refractory metals comprise the same metal.

1           55. The photonic crystal of claim 53, wherein the first and second  
2 refractory metals both comprise tungsten or an alloy thereof.

1           56. The photonic crystal of claim 52, further comprising a filling material  
2 disposed within the spherical voids, the filling material differing in refractive  
3 index from the first refractory metal.

1           57. The photonic crystal of claim 57, wherein the filling material  
2 substantially fills the spherical voids.

1           58. The photonic crystal of claim 52, wherein the filament core has a  
2 longitudinal axis and a selected crystallographic axis of the predetermined  
3 crystallographic lattice is aligned parallel to the longitudinal axis of the filament  
4 core.

1           59. The photonic crystal of claim 52, wherein the first refractory metal  
2 comprises tungsten or an alloy thereof.

1           60. A method of using a photonic crystal to reduce emission of selected  
2 wavelengths of radiation from a filament, the method comprising the steps of:  
3           a) providing a core filament and an electrical input connected to the core  
4 filament; and

5           b) cladding the core filament with a photonic crystal material which is  
6 operable to reduce emission of selected wavelengths of radiation during the  
7 resistance heating of the filament when electrical energy is conducted to the  
8 input and to the core filament.

1           61. The method of claim 61, wherein the core filament has a longitudinal  
2 axis and the photonic crystal material has crystallographic axes, the method  
3 further comprising the step of aligning a selected one of the crystallographic  
4 axes of the photonic crystal material parallel to the longitudinal axis of the core  
5 filament.

1           62. A method for filtering light from a light source having a longitudinal  
2 axis, comprising the steps of:

3           a) providing a photonic crystal having a predetermined crystallographic  
4 axis and a photonic band-gap adapted to block selected wavelengths of light;  
5 and

6           b) surrounding the light source with the photonic crystal while aligning the  
7 predetermined crystallographic axis parallel to the longitudinal axis of the light  
8 source.

1           63. A filament comprising, in combination:

2           a) elongated filamentary means for emitting radiation in a range of  
3 wavelengths in response to resistance heating; and

4           b) means for filtering, surrounding the filamentary means for emitting  
5 radiation, the filtering means comprising a photonic crystal, the photonic crystal  
6 being disposed surrounding the filamentary means for emitting radiation, and  
7 the photonic crystal having a band-gap adapted to reduce the emission of  
8 selected wavelengths at least partially within the range of wavelengths.

1           64. An electrical device comprising:

2           a) a support,

3           b) a transparent envelope secured to the support and forming an  
4 enclosure therewith,



5 c) a filament having a metal core portion, and

6 d) an input for electrical energy secured to the support and electrically

7 coupled to the filament, the metal core portion of the filament being coated with

8 a photonic crystal material which is effective in reducing emission of selected

9 wavelengths of radiation during the resistance heating of the filament when

10 electrical energy is conducted to the input and to the metal core portion of the

11 filament.

1 65. The electrical device of claim 65, wherein the selected wavelengths

2 of radiation are selected infrared wavelengths and the photonic crystal material

3 has a photonic band-gap corresponding to the selected infrared wavelengths.

1 66. The electrical device of claim 65, wherein the metal core portion of

2 the filament has a longitudinal axis, the photonic crystal material has

3 crystallographic axes, and a selected one of the crystallographic axes of the

4 photonic crystal material is aligned substantially parallel to the longitudinal axis

5 of the metal core portion of the filament.